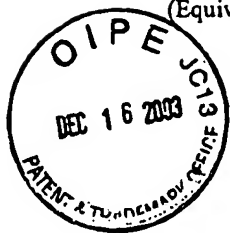


Atty. Docket No.
AM-8472



Sang H. Ahn et al.
Applicants

November 28, 2003
Filing Date

Unknown
Group

Examiner <u>Initial</u>	Document <u>Number</u>	Issue <u>Date</u>	<u>Name</u>	<u>Class</u>	<u>Subclass</u>	<u>Filing Date</u> <u>If Appropriate</u>
<u>WJ</u>	6,171,764	01/09/01	Ku et al.	430	322	_____
<u>WJ</u>	6,227,141	05/08/01	Sharan et al.	118	723 E	_____
<u>WJ</u>	6,607,984	08/19/03	Lee et al.	438	700	_____

<u>Examiner</u> <u>Initial</u>	<u>Document</u> <u>Number</u>	<u>Publication</u> <u>Date</u>	<u>Name</u>	<u>Class</u>	<u>Subclass</u>	<u>Filing Date</u>
<u>bu</u>	2003/0087518 A1	05/08/03	Chen et al.	438	637	11/08/01

Examiner
D. H. Haddock

05/24/05

Examiner: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

FOREIGN PATENT DOCUMENTS

<u>Examiner Initial</u>	<u>Document Number</u>	<u>Publication Date</u>	<u>Name</u>	<u>Class</u>	<u>Subclass</u>	<u>Translation If Appropriate</u>
<u>DD</u>	EP 1011135	06/21/00	Hsia et al.	H01L	21/768	_____
<u>DD</u>	WO 01/09683	02/08/01	Lee et al.	G03F	7/09	_____

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)

DD

J. E. Klemberg-Sapieha et al., "Dual Microwave-R.F. Plasma Deposition of Functional Coatings", Thin Solid Films, Vol. 193/194, pp. 965-972 (1990).

DD

A. Raveh et al., "Deposition and properties of diamondlike carbon films produced in microwave and radio-frequency plasma", J. Vac. Sci. Technol. A, Vol. 10, No. 4, pp. 1723-1727 (1992).

Examiner
Donald A. Chudis

Date Considered

05/24/05

Examiner: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.